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| Application Number | 10/613,700 |
| Filing Date | July 3, 2003 |
| First Named Inventor | Khursheed, Anjam |
| Art Unit | 2872 |
| Examiner Name | Not assigned yet |
| Attorney Docket Number | NAA 0016 PA/41049.18 |

NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| JB | | J. STOHR & S. SANDERS, "X-ray spectro-microscopy of complex materials and surfaces", IBM J. Res Develop, (2000), vol. 44, p. 535-551. | |
| JB | | Omicron Vakuumphysik GMBH, "Focus PEEM", January 2001, Germany | |
| JB | | D. PREIKSZAS et al., "SMART electron optics", 12th European Congress on Electron Microscopy, Proceedings Volume III, Instrumentation and Methodology, (2000), p. 18-84. | |
| JB | | H. SPIECKER et al., "Time-of-Flight Photoelectron Emission Microscopy TOF-PEEM: first results", Nucl. Instrum. and Methods in Phys. Res., (1998), A 406, p. 499-506. | |
| JB | | G.K.L. MARX et al., "Multipole WIEN-filter for a high-resolution X-PEEM", Journal of Electron Spectroscopy and Related Phenomena, (1997), Vol. 84, p. 251-61. | |
| JB | | A. KHURSHEED, "Ultimate resolution limits for scanning electron microscope immersion objective lenses," Optik, (2002), vol. 113, no. 2, p. 67-77. | |
| JB | | B.P. TONNER et al., "A Photoemission microscope with a hemispherical capacitor energy filter", Journal of Electron Spectroscopy & Related Phenomena, (1997), vol. 84, p. 211-29 | |
| JB | | J.E. Barth & P. Kruit, "Addition of different contributions to the charged particle probe size", Optik, (1996), vol. 101, no. 3, p. 101-109. | |
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|--------------------|-------------|-----------------|---------|
| Examiner Signature | Jack Berman | Date Considered | 6/28/04 |
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